



PATENT
Customer No. 22,852
Attorney Docket No. 08845.0015

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Jacob THAYSEN) Group Art Unit: Not yet assigned
Application No.: 10/539,820) Examiner: Not yet assigned
Filed: June 20, 2005)
For: A CANTILEVER SENSOR USING) Confirmation No.: Not yet assigned
BOTH THE LONGITUDINAL AND)
THE TRANSVERSAL)
PIEZORESISTIVE)
COEFFICIENTS)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), applicant brings to the attention of the Examiner the documents on the attached listing. This Information Disclosure Statement is being filed within three months of the date of entry of the national stage in an international application.

Copies of the listed foreign and non-patent literature documents are attached.

Copies of the U.S. patent publications are not enclosed.

Applicant respectfully requests that the Examiner consider the listed documents and indicate that they were considered by making appropriate notations on the attached form.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicant determines that the cited documents do not constitute "prior art" under United States law, applicant reserves the right to present to the office the relevant facts and law regarding the appropriate status of such documents.

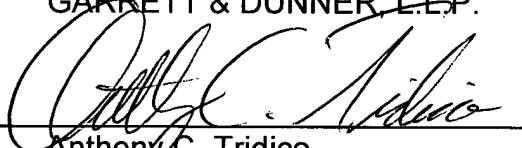
Applicant further reserves the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

By:


Anthony C. Tridico
Reg. No. 45,958

Dated: September 19, 2005

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Complete if Known

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

(Use as many sheets as necessary)

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of

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Application Number	10/539,820
Filing Date	June 20, 2005
First Named Inventor	Jacob THAYSEN
Art Unit	
Examiner Name	
Attorney Docket Number	08845.0015

U.S. PATENTS AND PUBLISHED U.S. PATENT APPLICATIONS

Examiner Initials	Cite No. ¹	Document Number	Issue or Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US-4,311,980	January 19, 1982	Prudenziati	
		US-5,275,055	January 4, 1994	Zook et al.	

Note: Submission of copies of U.S. Patents and published U.S. Patent Applications is not required.

FOREIGN PATENT DOCUMENTS

Examiner Initials	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Translation ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				
		WO03/067248 A1	August 14, 2003	CANTION A/S Scion. Dtu		
		WO03/062135 A1	July 31, 2003	CANTION A/S		
		WO03/104794 A1	December 18, 2003	CANTION A/S		
		WO03/071258 A1	August 28, 2003	CANTION A/S		
		WO00/14539	March 16, 2000	AEA TECHNOLOGY PLC		
		WO00/66266	November 9, 2000	GREY ET AL		
		WO03/044530 A1	May 30, 2003	CANTION A/S		
		WO99/38007	July 29, 1999	CAMBRIDGE UNIVERSITY TECHNICAL SERVICES LTD.		

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation ⁶
		H. Chen et al., "A Piezoresistive Accelerometer with a Novel Vertical Beam Structure", Sensors and Actuators, Vol. 63, pp. 19-25, 1997	
		Marc Madou: "Fundamentals of microfabrication" 1997, ISBN: 0-8493-9451-1, pp. 160-163.	
		Toriyama T et al: "Single crystal silicon nano-wire piezoresistors for mechanical sensors", Journal of Microelectromechanical Systems, IEEE, Vol. 11, No. 5, pp. 605-611, October 2002.	
		Harley J. A et al.: "1/f noise considerations for the design and process optimization of piezoresistive cantilevers", Journal of Microelectromechanical Systems IEEE, Vol. 9, No. 2, pp. 226-235, June 2000.	
		Jaeger R C et al.: "Off-axis sensor rosettes for measurement of the piezoresistive coefficients of silicon", IEEE Transactions on Components, Hybrids, and manufacturing Technology, Vol. 16, No. 8, pp. 925-931, Dec. 1993.	
		Jacob Thaysen "Cantilever for Bio-Chemical Sensing Integrated in a Microliquid Handling System". Ph.D Thesis, Mikroelektronik Centret, September 2001.	
		Stanley W. Polchlopek et al , "Properties of Nitrogen-Implanted SOI Substrates", IEEE Transaction on electron devices. Vol. 40.No. 2, February 1993.	
		Thaysen J. et al., "Atomic Force Microscopy probe with piezoresistive read-out and high symmetrical Wheatstone bridge arrangement" Proceedings of Transducers '99, 1252-1855, pp. 47-53, (1999).	
		Thaysen et al. "Cantilever-based bio-chemical sensor integrated in a microliquid handling system".	

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NON PATENT LITERATURE DOCUMENTS

	Technical Digest, 14 th IEEE. International conference on micro electro mechanical systems. ISBN: 0-7803-5998-4, . 2001.	
	Samuel Kassegne et al: "Design Issues in SOI-Based High-Sensitivity Piezoresistive Cantilever Devices" ; Nanogen Inc.	
	S. M. SZE, "Classification and terminology of sensors", Semiconductor Sensors, ISBN 0-471-54609-7, John Wiley & Sons Inc., pp. 160-169, 1994.	
	Y Kanda, "A graphical representation of the piezoresistance coefficients in silicon" IEEE Trans. Electron Devices, Vol. ED-29, pp. 64-70, Jan. 1982.	

Examiner Signature		Date Considered	
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.